



566.38683CX1

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants: YOSHIDA, et al.

Serial No.: 10/042,271

Filed: January 11, 2002

For: ABRASIVE METHOD OF POLISHING TARGET MEMBER AND
PROCESS FOR PRODUCING SEMICONDUCTOR DEVICE

Group: 3723

Examiner: Not yet assigned

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TECHNOLOGY CENTER R3700

INFORMATION DISCLOSURE STATEMENT
UNDER 37 CFR 1.97 & 1.98

Mail Stop DD
Assistant Commissioner of Patents
P.O. Box 1450
Alexandria, VA 22313-1450

February 10, 2004

Sir:

In the matter of the above-identified application, applicants are submitting herewith a copy of a communication from a foreign patent office in a counterpart foreign application and copies of the documents listed in the attached form equivalent to form PTO/SB/08A for the Examiner's consideration.

This information disclosure statement is being submitted on information and belief, before the mailing date of a first office action on the merits and is accompanied by the following certification specified in 37 CFR '1.97(e)

On information and belief, I hereby certify that no item of information in the information disclosure statement filed herewith was cited in a communication from a foreign patent office in a counterpart foreign application or, to my knowledge after making reasonable inquiry, was known to any individual designated in '1.56(c) more than three months prior to the filing of this information disclosure statement.

Each of the documents listed on the attached form equivalent to Form PTO/SB/08A is in the English language.

To the extent the documents listed on the attached form equivalent to form PTO/SB/08A are not in the English language, the requirement of 37 CFR '1.98(a)(3) for a concise explanation of the relevance is satisfied by an English language version or translation of the foreign patent office report citing the documents.

It is respectfully requested that this information disclosure statement be considered by the Examiner.

Please charge any shortage in the fees due in connection with the filing of this paper, including extension of time fees, to the deposit account of Antonelli, Terry, Stout & Kraus Deposit Account No. 01-2135 (566.38683CX1) please credit any excess fees to such deposit account.

Respectfully submitted,

ANTONELLI, TERRY, STOUT & KRAUS, LLP



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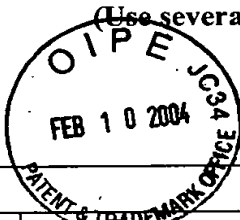
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INFORMATION DISCLOSURE CITATION BY APPLICANT

~~(Use several sheets if necessary)~~



Applicant
YOSHIDA, ET AL.

Filing Date	01/11/02
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Group
3723

U.S. PATENT DOCUMENTS

[illegible]

FOREIGN PATENT DOCUMENTS

[illegible]

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

	1.	1996 Proceedings First International Chemical-Mechanical Polish (C.M.P.) for VLSI/ULSI MULTILEVEL INTERCONNECTION CONFERENCE (CMP-MIC) " <i>Selective CMP of Organic Sog for Low Parasitic Capacitance Quarter-Micron Multilevel Interconnections</i> ", By: Yoshio HOMA, et al. Feb. 22-23, 1996

EXAMINER

DATE CONSIDERED